

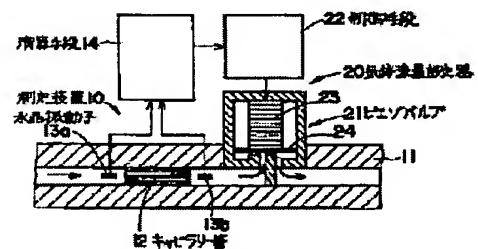
**METHOD AND APPARATUS FOR MEASURING FLOW RATE OF GAS AND GAS FLOW RATE SETTER**

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**Classification:**  
- **international:** G01F1/48; G01F1/00  
- **European:**  
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**PURPOSE:** To provide a method and an apparatus for measuring even the flow rate of an organic metal compound gas, having such physical properties as the molecular weight and viscosity are high and easily decomposed thermally, reliably and a setter for setting a flow rate accurately.

**CONSTITUTION:** In the method and apparatus for measuring the flow rate of gas, a capillary tube 12 is disposed in a piping 11 and the pressure difference across the capillary tube is detected based on the difference of frequency between a pair of quartz oscillators 13a, 13b disposed, respectively, in the upstream, and downstream of the capillary tube 12. An operating means 14 then operates the flow rate of gas flowing through the piping 14 based on the pressure difference thus detected. A gas flow rate setter 20 comprises a control means 22 for regulating the opening of a flow regulation valve based on the difference between a measured flow rate operated by the operating means 14 and a present flow rate..



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